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Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

- 1-26. (Cancelled)
- 27. (Currently amended) A method of fabricating a micro-mirror structure in a micro-mirror structures comprising:

forming a pyramidal structure from a first substrate material; and

defining electrodes on the pyramidal structure for positioning a mirror disposed adjacent
to the pyramidal structure.

- 28. (Original) The method of claim 27, wherein forming the pyramidal structure comprises: anisotropic etching the pyramidal structure to form steps of various depths in the structure.
- 29. (Currently amended) The method of claim 27, wherein the electrodes include four electrodes and forming the electrodes further comprises arranging arranging each electrode on a different one of quadrants of the pyramidal structure.
- 30. (Original) The method of claim 28, wherein the steps are polygonal in shape.
- 31. (Currently amended) The method of claim 27, wherein the substrate material is a first substrate material and wherein a second substrate material is bonded to the first substrate material.

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- 32. (Previously presented) The method of claim 31, wherein the second substrate material is a silicon-on-insulator wafer and is bonded to the first substrate material with a device side facing the wafer.
- 33. (Previously presented) The method of claim 31, further comprising:
 disposing a material to define the mirror in a surface of the second substrate material.
- 34. (Previously presented) The method of claim 31, further comprising: defining sensors in the surface of the second substrate material.
- 35. (Currently amended) The method of claim 27, further comprising:

 adding dam structures to at least one of the substrate materials material to isolate the micro-mirror structure from adjacent micro-mirror structures in a strip of micro-mirror structures.
- 36. (Previously presented) The method of claim 34, further comprising:

 defining other electronic components of the micro-mirror structures in one of the substrate materials.
- 37. (Withdrawn) A hinge comprising:
- a plurality of parallel hinge sections provided by vertical slots therein, the slots and parallel hinge sections being dimensioned to provide vertical and lateral stiffness to and a minimal torsion spring constant for the hinge.
- 38. (Currently amended) A micro-mirror assembly comprising: a frame;

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an array of two-dimensional deflecting mirrors mounted in the frame; and

blocking dams disposed between the mirrors to block viscous interaction between each of the two dimensional deflecting mirrors and adjacent ones of the two-dimensional deflecting mirrors in the array.